Graphene Growth "OCEAN CVD"



Features:

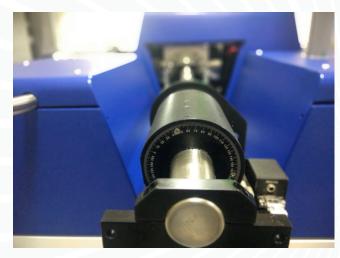
- Continuous Graphene / CNT / DLC Deposition, i.e., no reactor cool-down process.
- Distinct sample loading, unloading, transfer process using Load Lock chamber.
- Deposition on all Shapes of Wafers / Substrates upto 2.5" Diameter & 12" Length with constant temperature heating zone upto 1250°C.
- Gas Flow stabilization feature through Run / Vent line switching.
- Integrated Purifiers to eliminate gas impurities / contaminants.
- Customized Automation & Proprietary Recipe management through PLC/SCADA/HMI.
- Integrated in-situ Gas Leak monitoring & Exhaust Gas Abatement / Scrubber.
- Industrial Safety interlocks and Integrated and Detachable Gas Cabinets to house and supply 4 different gases
- Gas panel to control flow of 4 different gases.
- Reactor, single zone tube furnace with 3" quartz tube and water cooled flanges for continuous operations
- Plug and grow concept.
- Small foot print, clean room compatible, wheel mounted.
- Process recipes available and in constant development.

Options:

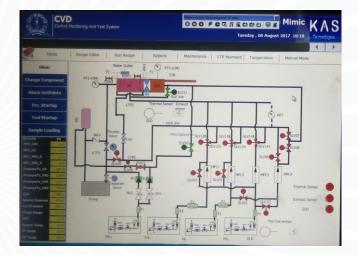
- Hook up of detachable gas cabinet from remote location.
- Independent gas cabinets and hook up.
- Additional purifier on inlet gases.
- Run-vent pressure equalization in gas flow panel.
- Scrubber on exhaust.
- Liquid and solid source integration.
- Kit for operating at pressure above atmospheric pressure and up to 1000 Torr.
- On-site training.

Please contact us if you are interested in the CVD equipment made in India

- The "Ocean" is an advantaedg turnkey thermal chemical vapor deposition process tool for synthesis of wide variety of low dimensional materials such as graphene and carbon nanotubes. The platform can be configured for growth of other emerging 2D materials as well.
- It needs only power, water and exhaust connections at the user end for installation and commissioning.
 A Continuous CVD option enables fast substrate heating and cooling by transferring samples into and out of the reactor without the need to cool down.
- Ocean CVD system is a low cost, small footprint, reliable and repeatable CVD system for the advance R & D user and a turn-key equipment for industrial run-through, with baseline process recipes and a proven safety systems



Loading System

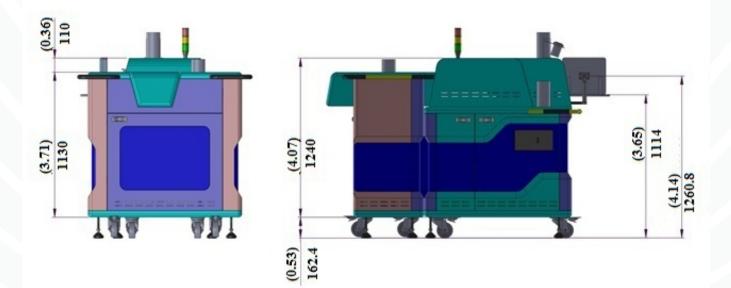


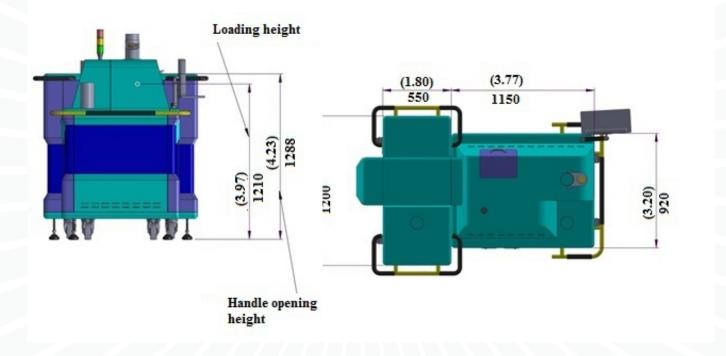
HMI Control System



Gas Panel

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Facility	Specifications	
Power	240V AC, 16 A, 50/60 Hz	
Water	3 LPM, 6 barg, 25C	
Exhaust	550 cfm@ 15 mm WC near the tool	